

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Mohn, et al.

Serial No.: 09/611,817

Confirmation No.: 6787

Filed: July 7, 2000

For: Multi-Purpose Processing Chamber  
with Removable Chamber Liner

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

Group Art Unit: 1763

Examiner: T. Dang

CERTIFICATE OF FACSIMILE  
TRANSMISSION UNDER 37 CFR 1.8

I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number indicated by the Examiner, namely, fax number 703/872-9311 to the attention of the named Examiner, on the date below.

6/21/02

Date

Signature

## RESPONSE TO OFFICE ACTION DATED MARCH 21, 2002

In response to the Office Action dated March 21, 2002, having a shortened statutory period for response set to expire on June 21, 2002, Applicant requests entry and consideration of the following amendments and remarks. Although Applicant believes that no fee is due in conjunction with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/4666/ETCH/CHMBR/JB1, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

IN THE CLAIMS:

Please cancel claim 33 without prejudice.

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1. An apparatus for processing a semiconductor substrate, comprising:  
a chamber body having an internal volume defined by first and second substantially cylindrical regions and by side walls extending between the first and second substantially cylindrical regions.